# Special Issue

# MEMS and NEMS Sensors: Innovations, Applications, and Future Directions in Micro/Nano Technologies

**Message from the Guest Editors**

This Special Issue seeks to highlight cutting-edge research addressing these challenges and showcasing breakthroughs in sensor design, fabrication, and applications. Contributions may explore novel materials, innovative fabrication techniques (e.g., nanolithography and 3D printing), or interdisciplinary solutions for integrating sensors with emerging technologies like AI, IoT, and wearable systems. Applications in biomedical diagnostics, environmental sensing, and industrial safety are of particular interest, as are studies on reliability, durability, and energy harvesting in NEMS.

By fostering collaboration among researchers, engineers, and industry leaders, this Special Issue aims to catalyze progress in MEMS/NEMS sensor technology, paving the way for next-generation smart systems and sustainable solutions. We invite submissions that advance both the science and practical deployment of these transformative technologies.

We look forward to receiving your submissions!

**Guest Editors**

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## Editor-in-Chief

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